Tokyo Electron’s History

Tokyo Electron continues to evolve, incorporating new technologies and concepts in response to the changing times with a focus on the semiconductor production equipment field.

**Founding Era**

1963 | Tokyo Electron Laboratories, Inc. (TEL) established and registered with a capital of five million yen.
1964 | Starts importing and selling diffusion furnaces manufactured by Thermco Products Corp., taking its first step into the semiconductor production equipment import business.
1965 | Concludes an agency agreement with Fairchild Semiconductor Corp. to sell Fairchild’s IC testers in Japan.
1967 | Establishes Pan Electron Inc. to start selling Fairchild’s ICs.

**Major Business Transformation**

1968 | TEL-Thermco Engineering Co., Ltd. (TEL-Thermco) established as a joint venture with Thermco Products Corp. and starts producing diffusion furnaces in Japan.
1972 | Tokyo Process Development Inc. established and starts import and sale of analysis equipment. TEL headquarters moved to the Meiho Building in Shinjuku, Tokyo.
1975 | Withdraws from production and export of consumer electronic goods, such as car radios and calculators, which accounted for 60% of sales.
1976 | TEL-Thermco develops the world’s first high-pressure oxidation system.

**Manufacturing Functions Reinforced**

1980 | Listed on the second section of the Tokyo Stock Exchange (TSE).
1981 | TEL-GenRad Ltd. established and starts production of in-circuit board testers in Japan.
1984 | Listed on the first section of the Tokyo Stock Exchange.
1986 | Central Research Laboratory facilities in Yamanashi Prefecture completed.

**In-house Production Expanded**

1988 | TEL-Thermco Engineering Co. Ltd. purchased from Thermco Products Corp. and turned into 100%-owned subsidiary.
1989 | Starts shipment of the CLEAN TRACK MARK-V, coater/developers.
1990 | Makes a full-scale entry into the LCD production equipment market.

**Era of Globalization**

1993 | Tokyo Electron FE Korea Limited (currently Tokyo Electron Korea Ltd.) established.
1994 | Standards, Environment, & Safety Center (currently Environment, Health & Safety Center) established.
1996 | Tokyo Electron America, Inc.’s new headquarters building and training center completed.
1997 | Tokyo Electron Tohoku Limited’s Sagami Plant becomes the first ISO14001-certified TEL Group company (all plants are subsequently acquiring ISO14001 certification).
1999 | Receives TSE’s Fourth Annual Award for Excellence in Disclosure.
2000 | Receives TSE’s 10th Disclosure Award (for the second time after 1999).
2001 | Establishes new corporate message “PEOPLE. TECHNOLOGY. COMMITMENT.”
2003 | Receives the Japanese Prime Minister’s Award for its industry-academia-government cooperative development of a large-diameter, high-density plasma processing system.
2005 | Receives TSE’s 10th Disclosure Award (for the second time after 1999).
2006 | Establishes TEL Values.
2007 | Establishes TEL UNIVERSITY as an internal educational institution to provide employee training and education.
2009 | Concludes an agency agreement with Oerlikon Solar Ltd. to sell PV cell production equipment in the Asian and Oceanian regions.